manual wafer hot plate for up to 200mm wafers/substrates has been designed to meet the requirements of R&D work and small scale production and is available in bench mounted, table-top or stand-alone versions. The hot plate is equipped with lift pins as a standard, which permits convenient and safe substrate handling. Nitrogen purge and vacuum suction of the substrate can also be individually selected for each step in the recipe editor.

The closed double walled lid ensures stable process conditions and prevents accidental touching of the hot surface by the operator.

hot plate Product Features

1. 13.875 in (354.24 mm) diameter heater surface, Milled flat plate aluminum ideal for 12 in (304.8 mm) or smaller silicon wafers

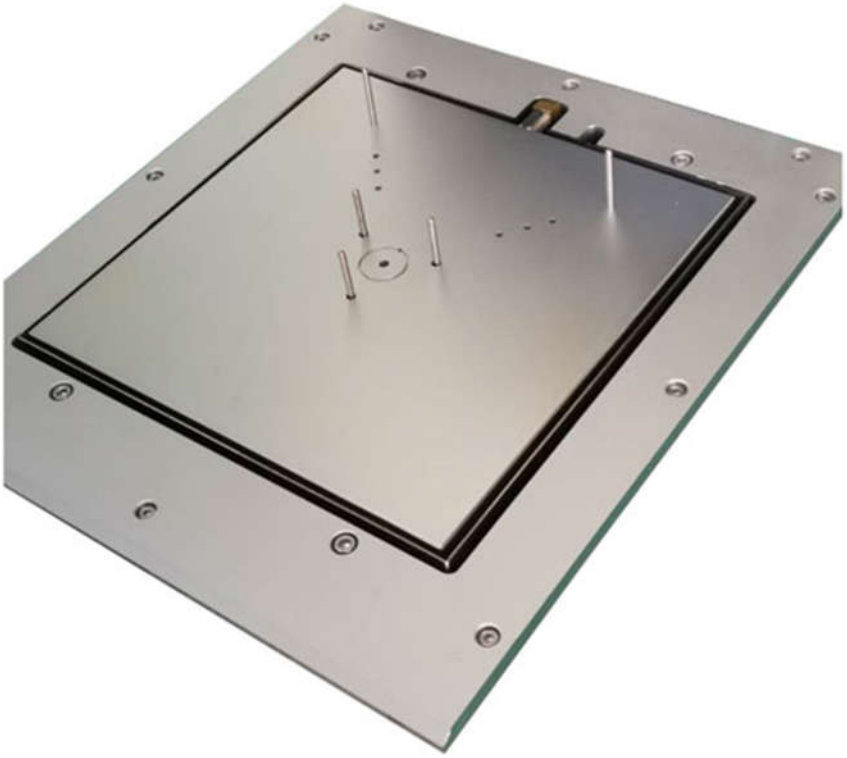
2. Controllable remotely from a PC or industrial controller via RS232 I/O port or via the Remote Controller Provided with full access to all parameters or data. Bench top controllable and programmable using the remote controller provided

3. Temperature range from room temperature to 350 ° C.

4. Readable and settable to 0.1 ° C, Accuracy 1% of setting

5.Temperature stability ± 1 ° C,Uniformity of temperature from the middle of the plate surface to within 0.75 in of the sides is better than 1%.Calibrated to 0.1 ° C for guaranteed accuracy

[caption id="attachment_18522" align="aligncenter" width="750"]



Heating plate module[/caption]

6.Remote controller enables storing 5 individual programs with up to 10 steps per program for a variety of hands-off, repeatable sample runs

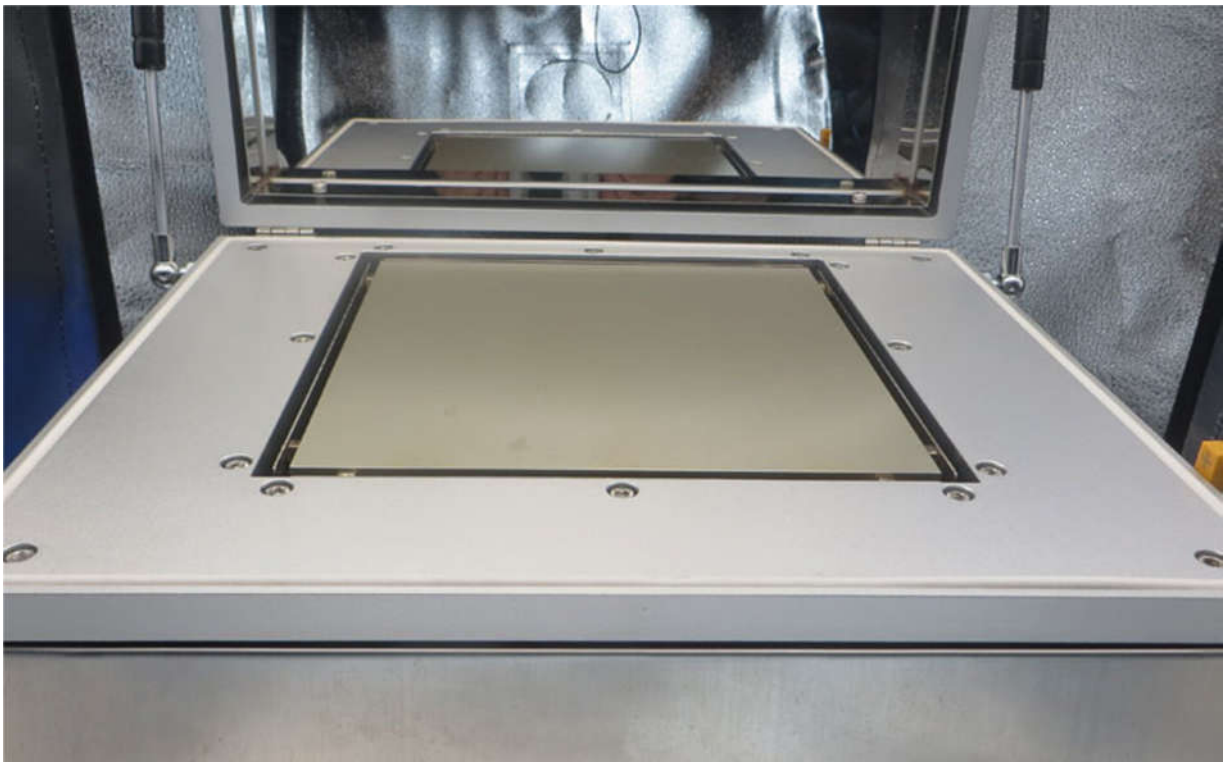
7.Programs automatically repeatable from 1 to 99 times or infinitely if wanted

8.Ramp temperatures up or down at 1 ° C/hour increments from 1 ° C to 450 ° C

9.1800 W heater power

10.Built-in count down timer with audible alarm and settable Auto-Off

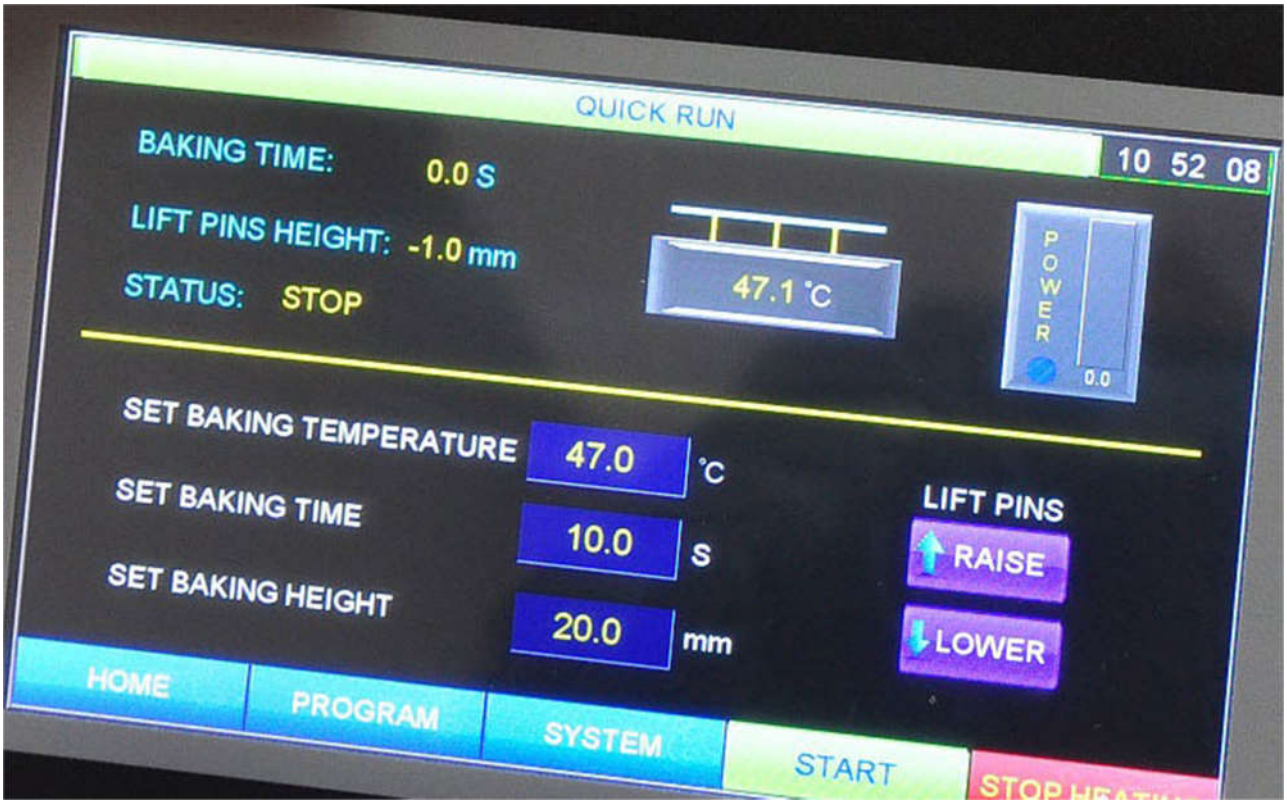
11.Compact dimension, can put in vacuum glove box



Specifications

Temperature	
Platinum RTD	100 Ω at zero mounted in the heater top
Range	10 °C to 350 °C on the plate surface
Readability	1 °C
Temperature control type	PID
Temperature stability	1 °C
Temperature Uniformity	Better than 1% of setting from center to within 0.75” of plate

Electrical	
Heater power	1500 W
VAC	115 VAC, 50/60 Hz (230 VAC available upon request)
Fused	Yes
Line Cord	Detachable, 6 ft (1.8 m), 3-wire grounded. Single phase
Dimensions: Heater Module	
Width	13.875 in (352.4 mm) circle
Height	5.75 in (146 mm)
Weight	21.5 lb (9.54 kg)



Applications

Cleaning silicon wafers

Drying silicon wafers

Etching silicon wafers

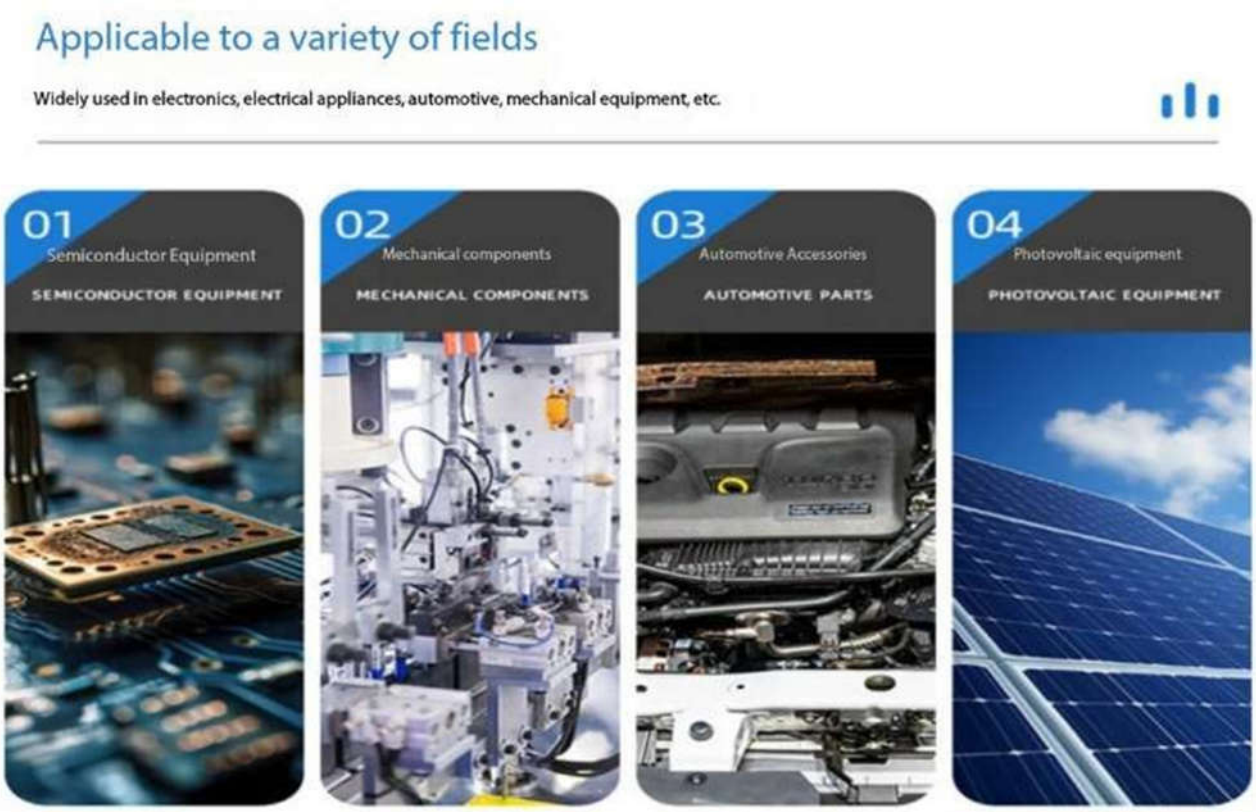
Heat testing circuits

Heat testing epoxies

Soldering surface mount PCB's

Life cycle testing of PCB's

Testing LCD's



Utilities

- voltage ranges： 100-120; 208-230 VAC
- power requirements:1800W (16.4A); 1800W (8.1A) max
- exhaust port: 2” OD
- vacuum:<33kPa abs
- exhaus: 5-10cfm
- N2:35psi